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NARODOWA STRATEGIA SPÓJNOŚCI

UNIA EUROPEJSKA
EUROPEJSKI FUNDUSZ
ROZWOJU REGIONALNEGO



DKZ/19/2009

Warsaw, 28.04.2009.

Re: The open procedure for delivery of the system for etching with use of focused ion beam (FIB).

With regard to the following questions:

1. *Is the digital electronic recording of images with maximal resolution at least 7 megapixels and at least 16-bit grayscale allowed? (Appendix 1, no 29).*
2. *Does the system should possess additionally the laser stage or piezo stage? (Appendix 1, no 27).*

we inform that:

Ad. 1

The Buyer does not allow the possibility to accept an offer for microscope system enabling digital electronic recording of images with maximal resolution at least 7 megapixels.

Ad. 2

The system have to be equipped with one stage that strictly fulfills requirements specified in the Terms of Reference.

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